

**AMENDED CLAIMS**

1. (Currently Amended) ~~Method~~ A method of producing a compact movable structure (40) for a light shaping unit comprising ~~the steps of:~~

forming a light shaping unit (12) ~~from a material (30) provided on a carrier (32, 34, 36)~~  
of another material, ~~(step 58),~~ and

forming a micromechanical structure (12, 16, 18, 22, 29, 28) from the carrier which is adapted to move the light shaping unit, ~~(step 60),~~

wherein the ~~forming of the~~ light shaping unit is formed ~~takes place~~ before the ~~forming of~~  
the micromechanical structure is formed.

2. (Currently Amended) ~~Method~~ The method according to claim 1, further ~~comprising the~~  
~~step of~~ depositing the material for the light shaping unit on the carrier ~~(56)~~.

3. (Currently Amended) ~~Method~~ The method according to claim 2, ~~wherein further~~  
comprising:

spinning the material for the light shaping unit ~~is spun~~ on the carrier.

4. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the light  
shaping unit is formed through embossing.

5. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the  
micromechanical structure is formed under the light shaping unit.

6. (Currently Amended) ~~Method~~ The method according to claim 5, wherein the forming of the micromechanical structure comprises forming the micromechanical structure from above.
7. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the forming of the micromechanical structure comprises forming ~~of an opening from~~ from the bottom of the carrier ~~(step 62)~~ in a direction towards the light shaping unit in order to provide a light passage channel.
8. (Currently Amended) ~~Method~~ The method according to claim 7, wherein the light shaping unit ~~(12)~~ serves as an etch stop in the forming of the opening.
9. (Currently Amended) ~~Method~~ The method according to claim 7 or 8, ~~wherein further comprising:~~  
attaching an optical component ~~(24) is attached~~ to the bottom side of the micromechanical structure ~~(step 66)~~ in order to enable ~~the~~ a projection of light on or ~~the~~ a reception of light from the light shaping unit through the light passage channel.
10. (Currently Amended) ~~Method~~ The method according to claim 7, wherein the light passage channel is a cavity.
11. (Currently Amended) ~~Method~~ The method according to claim 7, wherein the light passage channel is a waveguide.

12. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the material for the light shaping unit is a polymer.
13. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the carrier comprises silicon.
14. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the light shaping unit is a lens.